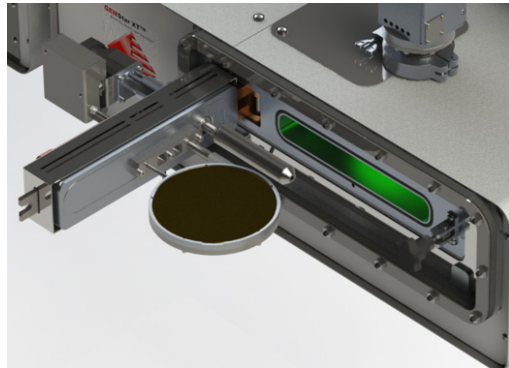


# GEMStar XT Particle Coating Door Option



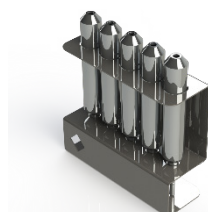
**Molecular Innovation™**



*The GEMStar XT HP ARR-850601-SR/HR option is designed to offer GEMStar XT Benchtop ALD Systems the ability to simultaneously process particles and 6" wafers both on a Desktop or attached to a Glovebox*

- ✦ Offered in both SR (300 °C) and HR (500 °C) versions for high temperature substrate coatings
- ✦ 60 RPM particle canister rotation for improved particle coating performance
- ✦ No tools required to load particle canister
- ✦ Replaces the standard XT door with 100% Wiring and Software Compatibility
- ✦ Compatible with glovebox interface option so particle and wafer processing/handling can be done in an inert gas environment
- ✦ Simultaneous metrology with QCM option mounted on standard metrology port

Particle Coating Door Option Specifications		
Option #	ARR-850601-SR	ARR-850601-HR
Compatibility	All XT System including PEALD except Load Lock Option	
Glovebox Interface	Yes	
Particle Process Volume	10 ml	
Particle Canister RPM	60 RPM (Adjustable to 200 RPM)	
Max Particle Process Temp	300°C	
Particle Process Type	Expo Method	
Rotational Vacuum Seal	Ferrofluidic	
Particle Canister Material	316L SS	
All Other Seal Material	DuPont™ Kalrez® Spectrum™ 7075	
Power Requirement (AC/DC Adapter Supplied)	120V AC 2.5A	
STD Substrate Size	150 mm (6")	
Max Substrate Process Temp	300°C	500°C
Batch Thermal Substrate Processing	YES	NO
Max Substrate Size	200 mm (8")	150 mm (6")



## **ARR-850615-HR**

*Particle Canisters are available in a 5 pack with holder*